
Contents

1	Data Acquisition	1
1.1	Sensors, Signals, and Systems	1
1.2	Sensor Classification	7
1.3	Units of Measurements	10
	References	11
2	Transfer Functions	13
2.1	Mathematical Models	13
2.1.1	Concept	15
2.1.2	Functional Approximations	15
2.1.3	Linear Regression	19
2.1.4	Polynomial Approximations	19
2.1.5	Sensitivity	21
2.1.6	Linear Piecewise Approximation	21
2.1.7	Spline Interpolation	22
2.1.8	Multidimensional Transfer Functions	23
2.2	Calibration	24
2.3	Computation of Parameters	26
2.4	Computation of a Stimulus	28
2.4.1	Use of Analytical Equation	29
2.4.2	Use of Linear Piecewise Approximation	29
2.4.3	Iterative Computation of Stimulus (Newton Method)	32
	References	34
3	Sensor Characteristics	35
3.1	Sensors for Mobile Communication Devices	35
3.1.1	Requirements to MCD Sensors	36
3.1.2	Integration	37
3.2	Span (Full-Scale Input)	38
3.3	Full-Scale Output	39
3.4	Accuracy	39
3.5	Calibration Error	42
3.6	Hysteresis	43
3.7	Nonlinearity	44
		vii

3.8	Saturation	45
3.9	Repeatability	46
3.10	Dead Band	47
3.11	Resolution	48
3.12	Special Properties	48
3.13	Output Impedance	48
3.14	Output Format	48
3.15	Excitation	49
3.16	Dynamic Characteristics	49
3.17	Dynamic Models of Sensor Elements	54
3.17.1	Mechanical Elements	54
3.17.2	Thermal Elements	55
3.17.3	Electrical Elements	57
3.17.4	Analogies	58
3.18	Environmental Factors	58
3.19	Reliability	61
3.19.1	MTTF	61
3.19.2	Extreme Testing	62
3.19.3	Accelerated Life Testing	63
3.20	Application Characteristics	65
3.21	Uncertainty	65
	References	67
4	Physical Principles of Sensing	69
4.1	Electric Charges, Fields, and Potentials	70
4.2	Capacitance	76
4.2.1	Capacitor	78
4.2.2	Dielectric Constant	79
4.3	Magnetism	83
4.3.1	Faraday Law	86
4.3.2	Permanent Magnets	88
4.3.3	Coil and Solenoid	89
4.4	Induction	90
4.4.1	Lenz Law	94
4.4.2	Eddy Currents	95
4.5	Resistance	96
4.5.1	Specific Resistivity	98
4.5.2	Temperature Sensitivity of a Resistor	99
4.5.3	Strain Sensitivity of a Resistor	102
4.5.4	Moisture Sensitivity of a Resistor	104
4.6	Piezoelectric Effect	104
4.6.1	Ceramic Piezoelectric Materials	108
4.6.2	Polymer Piezoelectric Films	112
4.7	Pyroelectric Effect	113
4.8	Hall Effect	119

4.9	Thermoelectric Effects	123
4.9.1	Seebeck Effect	123
4.9.2	Peltier Effect	128
4.10	Sound Waves	129
4.11	Temperature and Thermal Properties of Materials	132
4.11.1	Temperature Scales	133
4.11.2	Thermal Expansion	135
4.11.3	Heat Capacity	137
4.12	Heat Transfer	138
4.12.1	Thermal Conduction	139
4.12.2	Thermal Convection	141
4.12.3	Thermal Radiation	142
	References	153
5	Optical Components of Sensors	155
5.1	Light	155
5.1.1	Energy of Light Quanta	155
5.1.2	Light Polarization	157
5.2	Light Scattering	157
5.3	Geometrical Optics	159
5.4	Radiometry	160
5.5	Photometry	166
5.6	Windows	169
5.7	Mirrors	171
5.7.1	Coated Mirrors	172
5.7.2	Prismatic Mirrors	173
5.8	Lenses	174
5.8.1	Curved Surface Lenses	174
5.8.2	Fresnel Lenses	176
5.8.3	Flat Nanolenses	179
5.9	Fiber Optics and Waveguides	179
5.10	Optical Efficiency	183
5.10.1	Lensing Effect	183
5.10.2	Concentrators	185
5.10.3	Coatings for Thermal Absorption	186
5.10.4	Antireflective Coating (ARC)	187
	References	188
6	Interface Electronic Circuits	191
6.1	Signal Conditioners	193
6.1.1	Input Characteristics	194
6.1.2	Amplifiers	198
6.1.3	Operational Amplifiers	199
6.1.4	Voltage Follower	201

6.1.5	Charge- and Current-to-Voltage Converters	201
6.1.6	Light-to-Voltage Converters	203
6.1.7	Capacitance-to-Voltage Converters	205
6.1.8	Closed-Loop Capacitance-to-Voltage Converters . . .	207
6.2	Sensor Connections	209
6.2.1	Ratiometric Circuits	209
6.2.2	Differential Circuits	212
6.2.3	Wheatstone Bridge	212
6.2.4	Null-Balanced Bridge	215
6.2.5	Bridge Amplifiers	216
6.3	Excitation Circuits	218
6.3.1	Current Generators	220
6.3.2	Voltage Generators	222
6.3.3	Voltage References	223
6.3.4	Oscillators	224
6.4	Analog-to-Digital Converters	225
6.4.1	Basic Concepts	226
6.4.2	V/F Converters	227
6.4.3	PWM Converters	231
6.4.4	R/F Converters	232
6.4.5	Successive-Approximation Converter	234
6.4.6	Resolution Extension	235
6.4.7	ADC Interface	237
6.5	Integrated Interfaces	239
6.5.1	Voltage Processor	239
6.5.2	Inductance Processor	240
6.6	Data Transmission	241
6.6.1	Two-Wire Transmission	242
6.6.2	Four-Wire Transmission	243
6.7	Noise in Sensors and Circuits	243
6.7.1	Inherent Noise	244
6.7.2	Transmitted Noise	247
6.7.3	Electric Shielding	252
6.7.4	Bypass Capacitors	255
6.7.5	Magnetic Shielding	256
6.7.6	Mechanical Noise	258
6.7.7	Ground Planes	258
6.7.8	Ground Loops and Ground Isolation	259
6.7.9	Seebeck Noise	261
6.8	Batteries for Low-Power Sensors	263
6.8.1	Primary Cells	264
6.8.2	Secondary Cells	265
6.8.3	Supercapacitors	265

6.9	Energy Harvesting	266
6.9.1	Light Energy Harvesting	267
6.9.2	Far-Field Energy Harvesting	268
6.9.3	Near-Field Energy Harvesting	269
	References	269
7	Detectors of Humans	271
7.1	Ultrasonic Detectors	273
7.2	Microwave Motion Detectors	276
7.3	Micropower Impulse Radars	281
7.4	Ground Penetrating Radars	284
7.5	Linear Optical Sensors (PSD)	285
7.6	Capacitive Occupancy Detectors	289
7.7	Triboelectric Detectors	292
7.8	Optoelectronic Motion Detectors	294
7.8.1	Sensor Structures	295
7.8.2	Multiple Detecting Elements	297
7.8.3	Complex Sensor Shape	297
7.8.4	Image Distortion	297
7.8.5	Facet Focusing Elements	298
7.8.6	Visible and Near-IR Light Motion Detectors	299
7.8.7	Mid- and Far-IR Detectors	301
7.8.8	Passive Infrared (PIR) Motion Detectors	302
7.8.9	PIR Detector Efficiency Analysis	305
7.9	Optical Presence Sensors	309
7.9.1	Photoelectric Beam	309
7.9.2	Light Reflection Detectors	310
7.10	Pressure-Gradient Sensors	311
7.11	2-D Pointing Devices	313
7.12	Gesture Sensing (3-D Pointing)	314
7.12.1	Inertial and Gyroscopic Mice	315
7.12.2	Optical Gesture Sensors	315
7.12.3	Near-Field Gesture Sensors	316
7.13	Tactile Sensors	318
7.13.1	Switch Sensors	319
7.13.2	Piezoelectric Tactile Sensors	320
7.13.3	Piezoresistive Tactile Sensors	323
7.13.4	Tactile MEMS Sensors	326
7.13.5	Capacitive Touch Sensors	326
7.13.6	Optical Touch Sensors	330
7.13.7	Optical Fingerprint Sensors	331
	References	332

8	Presence, Displacement, and Level	335
8.1	Potentiometric Sensors	336
8.2	Piezoresistive Sensors	340
8.3	Capacitive Sensors	342
8.4	Inductive and Magnetic Sensors	345
8.4.1	LVDT and RVDT	346
8.4.2	Transverse Inductive Sensor	348
8.4.3	Eddy Current Probes	349
8.4.4	Pavement Loops	351
8.4.5	Metal Detectors	352
8.4.6	Hall-Effect Sensors	353
8.4.7	Magnetoresistive Sensors	358
8.4.8	Magnetostrictive Detector	361
8.5	Optical Sensors	362
8.5.1	Optical Bridge	363
8.5.2	Proximity Detector with Polarized Light	363
8.5.3	Prismatic and Reflective Sensors	364
8.5.4	Fabry-Perot Sensors	366
8.5.5	Fiber Bragg Grating Sensors	368
8.5.6	Grating Photomodulators	370
8.6	Thickness and Level Sensors	371
8.6.1	Ablation Sensors	372
8.6.2	Film Sensors	373
8.6.3	Cryogenic Liquid Level Sensors	375
	References	376
9	Velocity and Acceleration	379
9.1	Stationary Velocity Sensors	382
9.1.1	Linear Velocity	382
9.1.2	Rotary Velocity Sensors (Tachometers)	384
9.2	Inertial Rotary Sensors	385
9.2.1	Rotor Gyroscope	386
9.2.2	Vibrating Gyroscopes	387
9.2.3	Optical (Laser) Gyroscopes	390
9.3	Inertial Linear Sensors (Accelerometers)	392
9.3.1	Transfer Function and Characteristics	393
9.3.2	Inclinometers	397
9.3.3	Seismic Sensors	400
9.3.4	Capacitive Accelerometers	401
9.3.5	Piezoresistive Accelerometers	404
9.3.6	Piezoelectric Accelerometers	405
9.3.7	Thermal Accelerometers	406
9.3.8	Closed-Loop Accelerometers	410
	References	411

10	Force and Strain	413
10.1	Basic Considerations	413
10.2	Strain Gauges	416
10.3	Pressure-Sensitive Films	418
10.4	Piezoelectric Force Sensors	420
10.5	Piezoelectric Cables	424
10.6	Optical Force Sensors	426
	References	428
11	Pressure Sensors	429
11.1	Concept of Pressure	429
11.2	Units of Pressure	431
11.3	Mercury Pressure Sensor	432
11.4	Bellows, Membranes, and Thin Plates	433
11.5	Piezoresistive Sensors	435
11.6	Capacitive Sensors	440
11.7	VRP Sensors	442
11.8	Optoelectronic Pressure Sensors	443
11.9	Indirect Pressure Sensor	445
11.10	Vacuum Sensors	447
11.10.1	Pirani Gauge	447
11.10.2	Ionization Gauges	449
11.10.3	Gas Drag Gauge	450
	References	451
12	Flow Sensors	453
12.1	Basics of Flow Dynamics	453
12.2	Pressure Gradient Technique	456
12.3	Thermal Transport Sensors	458
12.3.1	Hot-Wire Anemometers	459
12.3.2	Three-Part Thermoanemometer	463
12.3.3	Two-Part Thermoanemometer	465
12.3.4	Microflow Thermal Transport Sensors	468
12.4	Ultrasonic Sensors	470
12.5	Electromagnetic Sensors	472
12.6	Breeze Sensor	474
12.7	Coriolis Mass Flow Sensors	475
12.8	Drag Force Flowmeter	477
12.9	Cantilever MEMS Sensors	478
12.10	Dust and Smoke Detectors	479
12.10.1	Ionization Detector	479
12.10.2	Optical Detector	481
	References	483

13	Microphones	485
13.1	Microphone Characteristics	487
13.1.1	Output Impedance	487
13.1.2	Balanced Output	487
13.1.3	Sensitivity	487
13.1.4	Frequency Response	488
13.1.5	Intrinsic Noise	488
13.1.6	Directionality	489
13.1.7	Proximity Effect	492
13.2	Resistive Microphones	493
13.3	Condenser Microphones	493
13.4	Electret Microphones	495
13.5	Optical Microphones	497
13.6	Piezoelectric Microphones	500
13.6.1	Low-Frequency Range	500
13.6.2	Ultrasonic Range	501
13.7	Dynamic Microphones	504
	References	505
14	Humidity and Moisture Sensors	507
14.1	Concept of Humidity	507
14.2	Sensor Concepts	511
14.3	Capacitive Humidity Sensors	512
14.4	Resistive Humidity Sensors	515
14.5	Thermal Conductivity Sensor	516
14.6	Optical Hygrometers	517
14.6.1	Chilled Mirror	517
14.6.2	Light RH Sensors	518
14.7	Oscillating Hygrometer	519
14.8	Soil Moisture	520
	References	523
15	Light Detectors	525
15.1	Introduction	525
15.1.1	Principle of Quantum Detectors	526
15.2	Photodiode	530
15.3	Phototransistor	536
15.4	Photoresistor	538
15.5	Cooled Detectors	540
15.6	Imaging Sensors for Visible Range	543
15.6.1	CCD Sensor	544
15.6.2	CMOS Imaging Sensors	545
15.7	UV Detectors	546
15.7.1	Materials and Designs	546
15.7.2	Avalanche UV Detectors	547

15.8	Thermal Radiation Detectors	549
15.8.1	General Considerations	549
15.8.2	Golay Cells	551
15.8.3	Thermopiles	552
15.8.4	Pyroelectric Sensors	558
15.8.5	Microbolometers	564
	References	567
16	Detectors of Ionizing Radiation	569
16.1	Scintillating Detectors	570
16.2	Ionization Detectors	574
16.2.1	Ionization Chambers	574
16.2.2	Proportional Chambers	575
16.2.3	Geiger–Müller (GM) Counters	576
16.2.4	Semiconductor Detectors	578
16.3	Cloud and Bubble Chambers	582
	References	583
17	Temperature Sensors	585
17.1	Coupling with Object	585
17.1.1	Static Heat Exchange	585
17.1.2	Dynamic Heat Exchange	589
17.1.3	Sensor Structure	592
17.1.4	Signal Processing of Sensor Response	594
17.2	Temperature References	596
17.3	Resistance Temperature Detectors (RTD)	597
17.4	Ceramic Thermistors	599
17.4.1	Simple Model	601
17.4.2	Fraden Model	602
17.4.3	Steinhart and Hart Model	604
17.4.4	Self-Heating Effect in NTC Thermistors	607
17.4.5	Ceramic PTC Thermistors	611
17.4.6	Fabrication	615
17.5	Silicon and Germanium Thermistors	617
17.6	Semiconductor <i>pn</i> -Junction Sensors	620
17.7	Silicon PTC Temperature Sensors	624
17.8	Thermoelectric Sensors	626
17.8.1	Thermoelectric Laws	628
17.8.2	Thermocouple Circuits	630
17.8.3	Thermocouple Assemblies	633
17.9	Optical Temperature Sensors	635
17.9.1	Fluoroptic Sensors	635
17.9.2	Interferometric Sensors	637
17.9.3	Super-High Resolution Sensing	637
17.9.4	Thermochromic Sensors	638
17.9.5	Fiber-Optic Temperature Sensors (FBG)	639

17.10	Acoustic Temperature Sensors	640
17.11	Piezoelectric Temperature Sensors	641
	References	642
18	Chemical and Biological Sensors	645
18.1	Overview	646
18.1.1	Chemical Sensors	646
18.1.2	Biochemical Sensors	647
18.2	History	647
18.3	Chemical Sensor Characteristics	648
18.3.1	Selectivity	648
18.3.2	Sensitivity	650
18.4	Electrical and Electrochemical Sensors	651
18.4.1	Electrode Systems	651
18.4.2	Potentiometric Sensors	655
18.4.3	Conductometric Sensors	656
18.4.4	Metal Oxide Semiconductor (MOS) Chemical Sensors	661
18.4.5	Elastomer Chemiresistors	663
18.4.6	Chemicapacitive Sensors	666
18.4.7	ChemFET	668
18.5	Photoionization Detectors	669
18.6	Physical Transducers	671
18.6.1	Acoustic Wave Devices	671
18.6.2	Microcantilevers	674
18.7	Spectrometers	676
18.7.1	Ion Mobility Spectrometry	677
18.7.2	Quadrupole Mass Spectrometer	678
18.8	Thermal Sensors	679
18.8.1	Concept	679
18.8.2	Pellister Catalytic Sensors	680
18.9	Optical Transducers	681
18.9.1	Infrared Detection	681
18.9.2	Fiber-Optic Transducers	682
18.9.3	Ratiometric Selectivity (Pulse Oximeter)	683
18.9.4	Color Change Sensors	686
18.10	Multi-sensor Arrays	688
18.10.1	General Considerations	688
18.10.2	Electronic Noses and Tongues	688
18.11	Specific Difficulties	692
	References	693
19	Materials and Technologies	699
19.1	Materials	699
19.1.1	Silicon as Sensing Material	699
19.1.2	Plastics	703

19.1.3	Metals	708
19.1.4	Ceramics	710
19.1.5	Structural Glasses	710
19.1.6	Optical Glasses	711
19.2	Nano-materials	714
19.3	Surface Processing	715
19.3.1	Spin Casting	715
19.3.2	Vacuum Deposition	716
19.3.3	Sputtering	717
19.3.4	Chemical Vapor Deposition (CVD)	718
19.3.5	Electroplating	719
19.4	MEMS Technologies	721
19.4.1	Photolithography	722
19.4.2	Silicon Micromachining	723
19.4.3	Micromachining of Bridges and Cantilevers	727
19.4.4	Lift-Off	728
19.4.5	Wafer Bonding	729
19.4.6	LIGA	730
	References	731
	Appendix	733
	Index	753

